

## CLAIMS

We claim:

1 1. A method for monitoring the condition of a fluid dielectric in an RF system  
2 comprising the steps of:  
3 transmitting optical radiation through a portion of said fluid dielectric contained  
4 within a dielectric substrate of said RF system;  
5 measuring at least one parameter indicative of a change of transmission direction  
6 of said optical radiation caused by said fluid dielectric.

1 2. The method according to claim 1 further comprising the step of selecting a  
2 material for said dielectric substrate to be a low temperature cofired ceramic.

1 3. The method according to claim 1 further comprising the step of comparing said  
2 change in direction to an expected change of direction for said fluid dielectric in a non-  
3 degraded condition.

1 4. The method according to claim 1 further comprising the step of calculating a  
2 refractive index of said fluid dielectric.

1 5. The method according to claim 3 further comprising the step of comparing said  
2 refractive index to an expected refractive index of said fluid dielectric in a non-degraded  
3 condition.

1 6. The method according to claim 1 further comprising the step of dynamically  
2 varying an angle of incidence of said transmitted optical radiation upon said fluid  
3 dielectric.

1 7. The method according to claim 6 further comprising the step of controlling a  
2 Micro-Opto-Electro-Mechanical System (MOEMS) to vary said angle of incidence.

1 8. The method according to claim 1 further comprising the step of selecting said  
2 optical radiation from the group consisting of infrared, ultraviolet, and visible light.

1 9. The method according to claim 1 further comprising the step of communicating a  
2 fault notification if a condition of said fluid dielectric is degraded.

1 10. The method according to claim 1 further comprising the step of determining a  
2 condition of said fluid dielectric based on said parameter.

1 11. The method according to claim 1 further comprising the step of modifying at least  
2 one operating parameter of said RF system if a condition of said fluid dielectric is  
3 determined to be degraded.

1 12. The method according to claim 11 wherein said at least one operating parameter  
2 that is modified is selected to compensate for an effect to said RF system caused by  
3 said fluid dielectric that is determined to be degraded.

- 1    13.    An RF system comprising:  
2            an RF circuit disposed on a dielectric substrate;  
3            a fluid dielectric contained within said dielectric substrate;  
4            a light source transmitting optical radiation through a portion of said fluid  
5    dielectric; and  
6            a sensor measuring at least one parameter indicative of a change of  
7    transmission direction of said optical radiation caused by said fluid dielectric.
- 1    14.    The RF system according to claim 13 wherein at least one of said light source  
2    and said sensor is embedded within said dielectric substrate.
- 1    15.    The RF system according to claim 13 wherein said substrate is a low  
2    temperature cofired ceramic.
- 1    16.    The RF system according to claim 13 wherein said processor compares said  
2    change of direction to an expected change of direction for said fluid dielectric in a non-  
3    degraded condition.
- 1    17.    The RF system according to claim 13 wherein said processor calculates a  
2    refractive index of said fluid dielectric.

1 18. The RF system according to claim 17 wherein said processor compares said  
2 refractive index to an expected refractive index of said fluid dielectric in a non-degraded  
3 condition.

1 19. The RF system according to claim 13 further comprising a light steering device  
2 responsive to a control signal, said light steering device selectively varying an angle of  
3 incidence of said transmitted optical radiation upon said fluid dielectric.

1 20. The RF system according to claim 19 wherein said light steering device  
2 comprises a Micro-Opto-Electro-Mechanical System (MOEMS) device.

1 21. The RF system according to claim 20 wherein said MOEMS device is embedded  
2 in a dielectric substrate of said RF system.

1 22. The RF system according to claim 13 wherein said optical radiation produced by  
2 said light source is selected from the group consisting of infrared, ultraviolet, and visible  
3 light.

1 23. The RF system according to claim 13 wherein said processor transmits a fault  
2 notification if a condition of said fluid dielectric is degraded.

1 24. The RF system according to claim 13 wherein at least one operating parameter  
2 of said RF system is modified if a condition of said fluid dielectric is determined to be  
3 degraded.

1 25. The RF system according to claim 24 wherein said at least one operating  
2 parameter that is modified is selected to compensate for an effect to said RF system  
3 caused by said fluid dielectric that is determined to be degraded.

1 26. The RF system according to claim 13 further comprising a processor responsive  
2 to an output of said sensor, said processor determining a condition of said fluid  
3 dielectric based on said parameter.

1 27. The RF system according to claim 26 wherein said condition affects at least one  
2 electrical characteristic of said fluid dielectric.

1 28. The RF system according to claim 26 wherein said electrical characteristic is at  
2 least one of a permittivity and a permeability.